

1762



35.C15381

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO, ET AL.

Application No.: 09,865,549

Filed: May 29, 2001

For: METHOD OF FORMING
SILICON-BASED THIN FILM,
SILICON-BASED THIN FILM
AND PHOTOVOLTAIC
ELEMENT

)
: Examiner: Not Yet Assigned

)
: Group Art Unit: 1762

)
: August 13, 2001

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TC 1760

Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

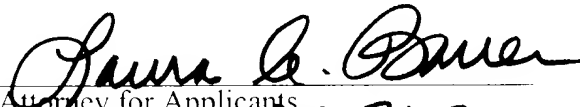
The concise explanation of relevance for the non-English document may be found in the specification at page 1, lines 18-24. Applicants have also provided an English abstract of this reference for the Examiner's convenience. Further, Applicants note that U.S. 5,387,542 cited in the Information Disclosure Statement dated May 25, 2001 is a counterpart to this Japanese patent document.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


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